

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Masahiko NAKAMORI, et al.
App. No	: 10/536,621
Filed	: May 26, 2005
For	: POLISHING PAD AND METHOD OF PRODUCING SEMICONDUCTOR DEVICE
Examiner	: Sylvia MacArthur
Art Unit	: 1792
Conf No.	: 9275

AMENDMENT ACCOMPANYING RCE**Mail Stop AF**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action, dated June 25, 2009, Applicant respectfully submits the following amendments and remarks in connection with the above-captioned application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.